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EUROPEAN PATENT APPLICATION

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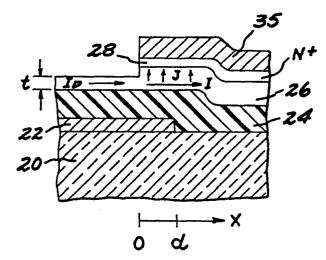
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(54) Low capacitance amorphous silicon field effect transistor structure.

(f) An amorphous silicon thin film FET is structured to be particularly useful for use in liquid crystal display circuits. In particular, critical FET dimensions are provided which permit optimal reduction of source to gate capacitance, while at the same time, preventing the occurrence of large contact voltage drops. Critical dimensions include active channel length, source-gate overlap, and amorphous silicon thickness. A critical relationship is established amongst these parameters.





EUROPEAN SEARCH REPORT

Application number

EP 86 11 0373

Category	Citation of document with indication, where appropriate, of relevant passages		Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int. Ct 4)	
A	APPLIED PHYSICS ASURFACES, vol. AS 1983, pages 87-92 Verlag, Heidelber MACKENZIE et al. characteristics as of optimised amorfield effect trans Pages 90-91, vestigation of figure 1 *	31, no. 2, June 2, Springer rg, DE; K.D. : "The and properties rphous silicon asistors" paragraph 3 "In-	1-3	H 01 L 29/78 H 01 L 29/06	
А	APPLIED PHYSICS LETTERS, vol. 36, no. 9, May 1980, pages 754-755, American Institute of Physics, New York, US; H. HAYAMA et al.: "Amorphous-silicon thin-film metal-oxide-semiconductor transistors" * Page 754, column 2, line 4;		1,3,4	TECHNICAL FIELDS SEARCHED (int. Ci.4)	
Α	figure 1 * PROCEEDINGS OF THE S.I.D., vol. 25, no. 1, 1984, SID, Los Angeles, California, US; K. SUZUKI et al.: "A 220 x 240 PIXEL a-Si TFT matrix transmission liquid crystal display" * Page 11, column 2 - page 12, column 2, line 31; figures 1,3 *		1,3,5	H O1 L	
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EUROPEAN SEARCH REPORT

EP 86 11 0373

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A	APPLIED PHYSICS I 45, no. 2, July 1 171-173, American Physics, New Yorl POWELL et al.: "Gof amorphous sile staggered-electron transistors" * Figures 1,2 *	LETTERS, vol. 1984, pages n Institute of k, US; M.J. Characteristics icon	1	TECHNICAL FIELDS SEARCHED (Int. Cl.4)
T	The present search report has been present search. Place of search. THE HAGUE	peen drawn up for all claims Date of completion of the search 21-09-1987		Examiner
1	THE HAGUE	21-09-1987	MORVA	N D.L.D.
Y: pa do A: te O: no	CATEGORY OF CITED DOCL articularly relevant if taken alone articularly relevant if combined w ocument of the same category chnological background on-written disclosure termediate document	E : earlier pa after the rith another D : documer L : documer	stent document, filing date nt cited in the ap nt cited for other of the same pate	lying the invention but published on, or plication reasons ent family, corresponding